IEEE SW Test Workshop Semiconductor Wafer Test Workshop



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Addressing the Operating Challenges of Full Wafer Contactors



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Outline

Probe cards are really challenging.
SmartMatrixTM &TouchMatrixTM Architecture Introduction
3 really challenging things:

Super Bond Pad
XY Tip Control
Z Tip Control

Conclusion



Probe cards are really challenging.

- A typical sheet of paper is ~100um thick.
- A typical ream of papers has 500 sheets.

100um

- Imagine you need to make an electrical connector to contact the edge of every single sheet in the ream.
- Now imagine the you need to make a connector to contact the edge of every sheet in 100 reams of paper = 50,000 contacts!

 The customer expects to be able to make more than 200,000 cycles on this connector.
 = 10 Million connections!

SmartMatrixTM & TouchMatrixTM Architecture

- Smaller Super Bond Pad
- Faster Soak Time
- Faster Installation Time
- Faster Lead Times
- Excellent CRES
- Wide Operating Temperature Range



FLASH platform TouchMatrix™ Contraction of the second sec

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What is a Super Bond Pad?

Step 1) Make a probe card (assume 50,000 probes)

Step 2) Touchdown on a hot wafer and measure bounding box of every single scrub mark (4 measurements: Top, Bottom, Left and Right)

Step 3) Repeat procedure for a cold wafer

Step 4) Take all 400,000 data points and combine these marks into one "Super Pad". Measure the bounding box. = Super Bond Pad = SBP

<u>SBP Non-Scrub</u> = Tip Width + Tip Width Tolerance + Tip placement accuracy + Scaling Error (Expected Temp x CTE) + Furrow + Prober Alignment <u>SBP Scrub</u> = Tip Length + Scrub Ratio x Overtravel + Tip Length Tolerance + Tip placement accuracy + Scaling Error (Expected Temp x CTE) + Prow + Prober Alignment





Dual Temp Super Bond Pad Capability

Super Bond Bad Performance Dual Temp DRAM Cards (100C-113C Range)



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Capable of 34um x 43um today for 100C dual temp range.

XY Tip position control - Scaling

- Traditional FWC: Probe Card not well matched to silicon wafer
 - Overscaled at hot test
 - Underscaled at cold test
- New Option 1: Dual temperature material
 - Exceptionally well matched to silicon wafer
 - Virtually no hot to cold scaling error.
- New Option 2: Single temperature material
 - True zero soak capability.
 - Ready to probe as soon as the card is loaded



Single and Dual Temperature Options

Single Temp Class I

- Zero Soak – ready to start testing as soon as the probecard is loaded.

- Less than 2um of movement at the edge of the wafer from room temperature to fully soaked.

- Less than 0.5 um of movement at the edge of the wafer during wafer change or lot change

Single Temp Class II

- Quick Soak from 5-30 mins depending on pad size and soak conditions.
- Typically 5-7um of movement at edge of wafer from room temp to fully soaked depending on test temperature

Dual Temp

- Optimized for hot and cold matched systems results in minimal scaling errors.
- Good stability during PMI and wafer changes.

Traditional FWC

- Non optimized material results in overshoot of center of pad.

- Lower thermal mass gets to temp quick but more motion of tips occurs during PMI and wafer changes.

Single Temp versus Dual Temp 6 4 edge of card (um) 2 0 -2 -4 -6 Wafer change -8 position at -10 — Single Temp-Class 1 -12 - Single Temp-Class 2 -14 - Dual Temp 16 -16 Traditional FWC -18 -20 fro -22 Distance -24 -26 -28 0 20 40 60 80 100 120 140 160 180 200 220 240 Time (mins)

Fastest soak & most stable system is Single Temp Class I

Best matched & widest temp range, is Dual Temp

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- Hot and cold touchdowns on one wafer.
- Scrub Marks overlap at center.
- Marks diverge as you get further form center of the wafer.
- Pad damage increases as marks diverge.



Dual Temperature Capability



- Dual temperature material provides exceptional scaling control across entire 300mm array.
- Hot touchdown on wafer.
 Scrub marks are well centered on pads.
- Same wafer cooled to -10C and another touchdown performed. Scrub marks in same position as they were at hot TD.
- Hot and cold marks overlap almost perfectly, minimizing pad damage.





- Step 1) Load a probe card at room temperature into a hot prober.
- Step 2) Make a touchdown immediately (Time 0)
- Step 3) Soak probe card until reaches steady state temperature
- Step 4) Make another touchdown at steady-state
- Step 5) Measure the marks from step 2 and step 4. At each location, calculate the total motion of the probes from time 0 to steady-state.
- Step 6) For each option, plot data as contour plots. Present data at SW Test. SWIW PAGE 11

Z tip control

Translation: When traditional probe cards are heated or cooled they will translate up or down because of the familiar bi-metal effect.



 Bow: The probe array may also be distorted from a perfectly flat plane due to thermal effects

Bow & Translation: Finally the probe array can be translated & distorted from a perfectly flat plane due to probe forces and forces imparted by the tester connections.





Z tip control

- Z translation of the probe card is optimized for each customer's test cell configuration thru careful design and thermal modeling.
- And we control the bow of the probe array from thermal effects to less than 5 microns.

 And we control planarity of all tips to <25 microns even while under load.





COLD -10C – Thermal Bow



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So if you choose a single temperature solution – you can start probing immediately!

Z Performance & Benefits

Minimizing 3 things: Translation, Bow and Planarity results in:

- More uniform scrub marks, minimized pad damage
- Faster soak time using closer proximity soak and/or contact soak.



New Architecture Adoption

 Announced in May 2010, we have shipped more than 100 TouchMatrix and SmartMatrix cards.

- Platform qualified or in qualification at all major DRAM and Flash manufacturers
- Multiple re-orders for many high running designs
- Many cards incorporate advanced tester resource extension electronics (A-TRETM) to increase native parallelism of testers.



Conclusion

- The SmartMatrix & TouchMatrix architecture address three really challenging <u>mechanical</u> things:
 - Super Bond Pad
 - Leading edge scrub capability
 - Minimizes pad damage
 - XY Tip Control
 - Scaling matched to silicon wafers (dual temperature)
 - Zero soak time (single temperature)
 - Thermally stable during wafer & lot change
 - Z Tip Control
 - Improved control of Z motion
 - Allows use of contact soak

There are also really challenging <u>electrical</u> things and <u>MEMS process</u> things that SmartMatrix & TouchMatrix address, but I'll save that for another talk...



Thank You!

